

# Characterization by IBIC of neutron irradiated SiC detectors at CNA

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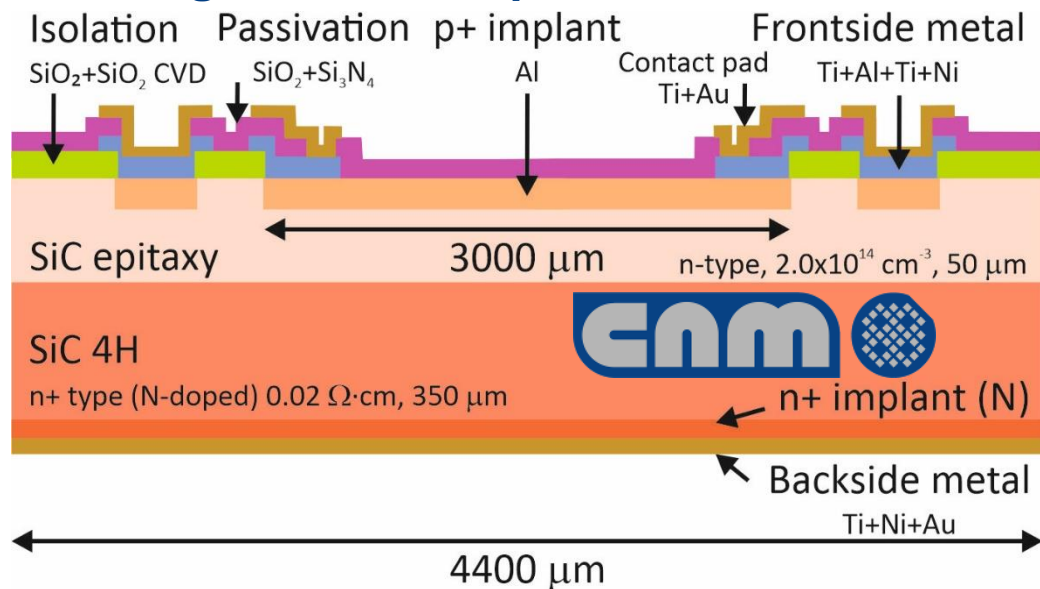
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# Context

## Design and development of devices



Characterization  
using laser  
(TPA-TCT)

**More info in Ivan Vila's  
talk!!**

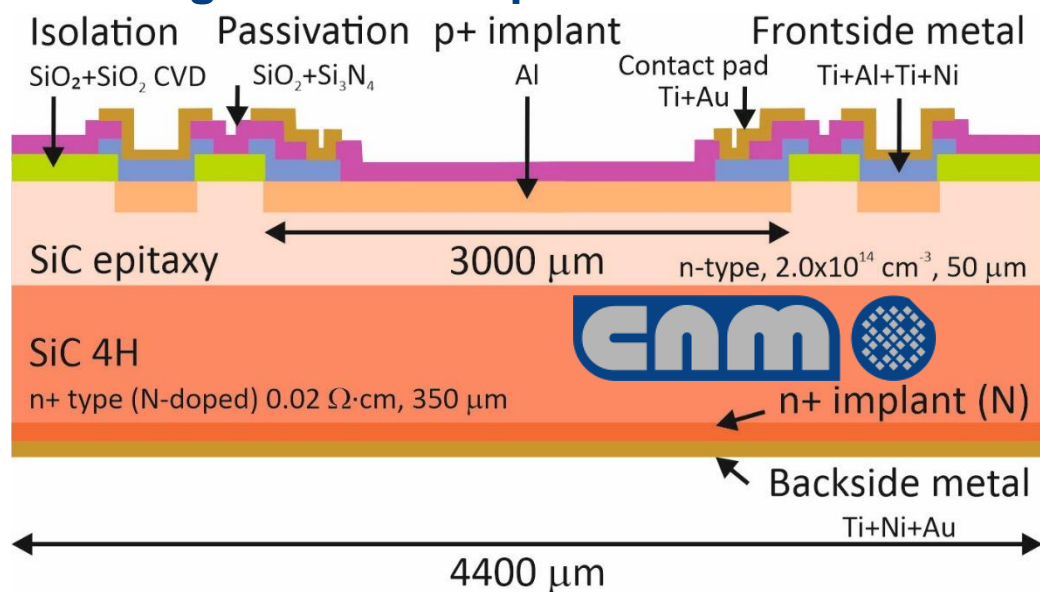
*"Observation of signal multiplication in  
neutron irradiated SiC detectors  
characterized using TPA-TCT"*

Characterization  
using ions (IBIC)

- C. Quintana et al, "Update on the characterization of neutron irradiated IMB-CNM SiC planar diodes", 41st RD50 Workshop (2022)
- E. Currás et al., "Radiation Tolerance Study of neutron-irradiated SiC pn planar diodes," 18th "Trento" Workshop (2023)

# Context

## Design and development of devices



Characterization using laser (TPA-TCT)

More info in Ivan Vila's talk!!

"Observation of signal multiplication in neutron irradiated SiC detectors characterized using TPA-TCT"

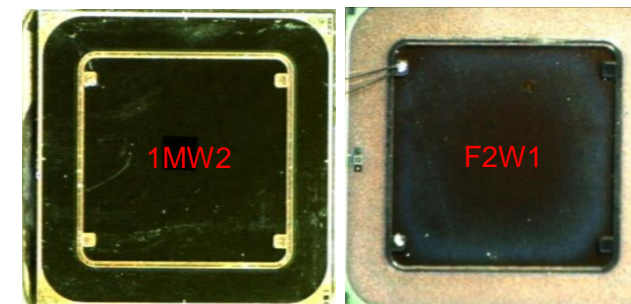
Characterization using ions (IBIC)

## Not metalized SiC detector

- 1MW2 (pristine)
- F2W1 ( $1 \times 10^{15} n_{eq}/cm^2$ )

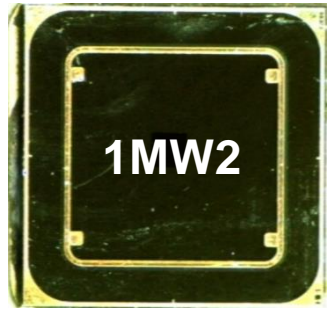
SiC epitaxy : 50 μm

Neutron irradiated detector does not present a diode-like behaviour

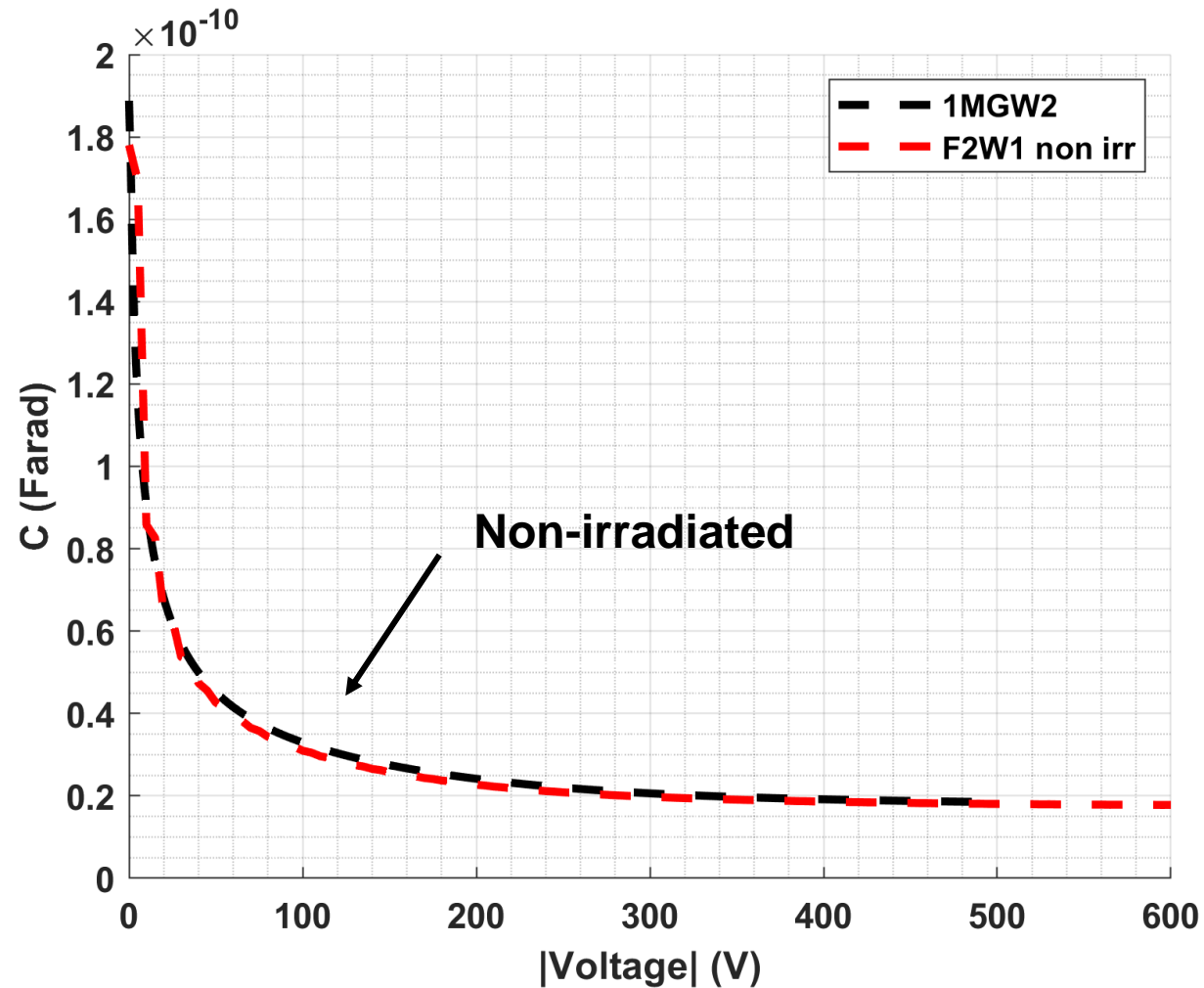


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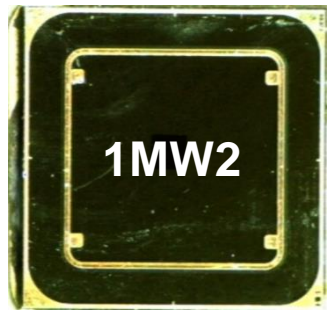
# Diode-like behaviour : non-irradiated



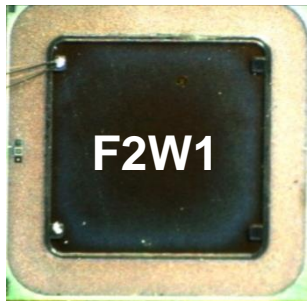
Pristine



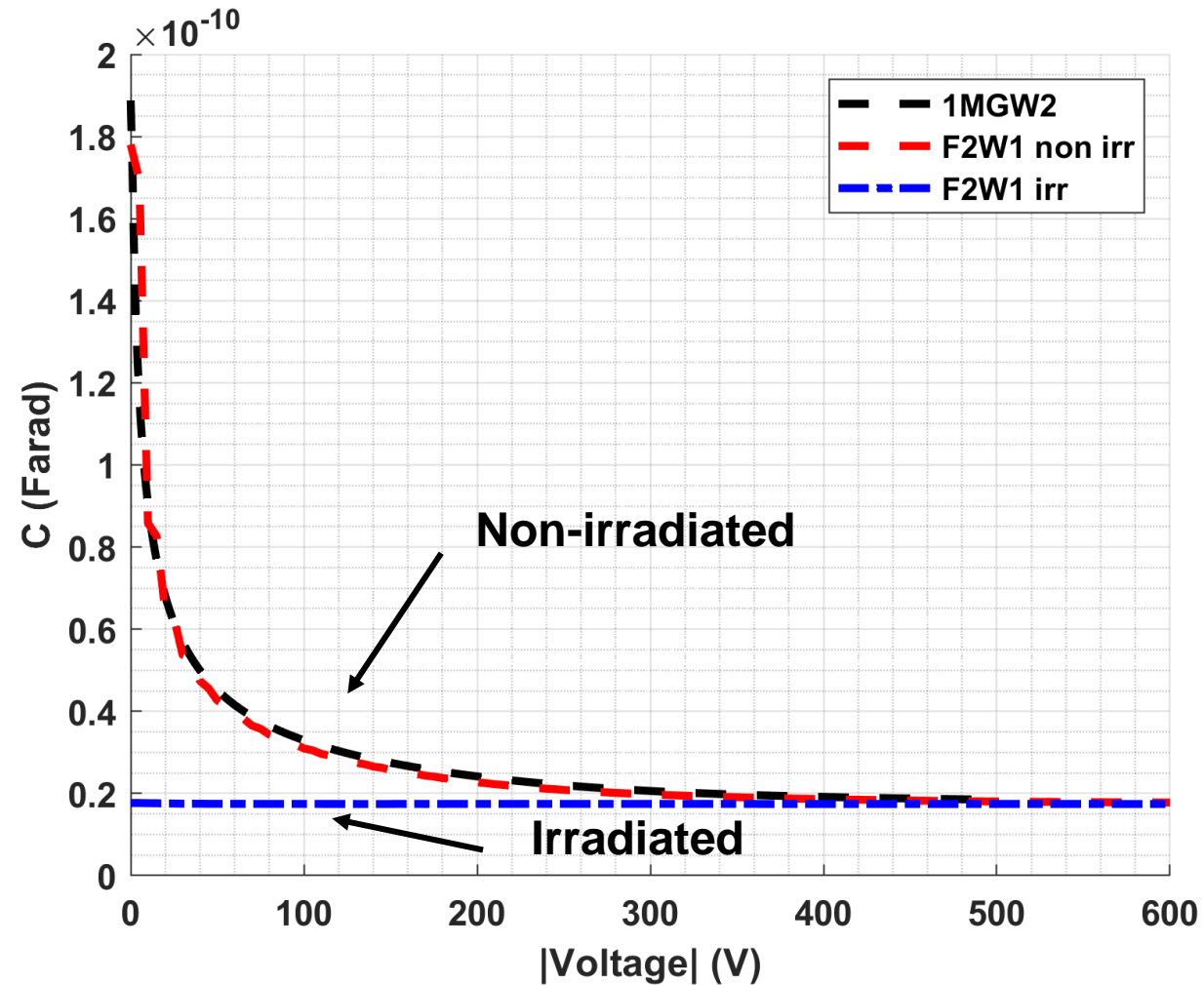
# No diode-like behaviour : irradiated



Pristine



$1 \times 10^{15} n_{eq}/cm^2$

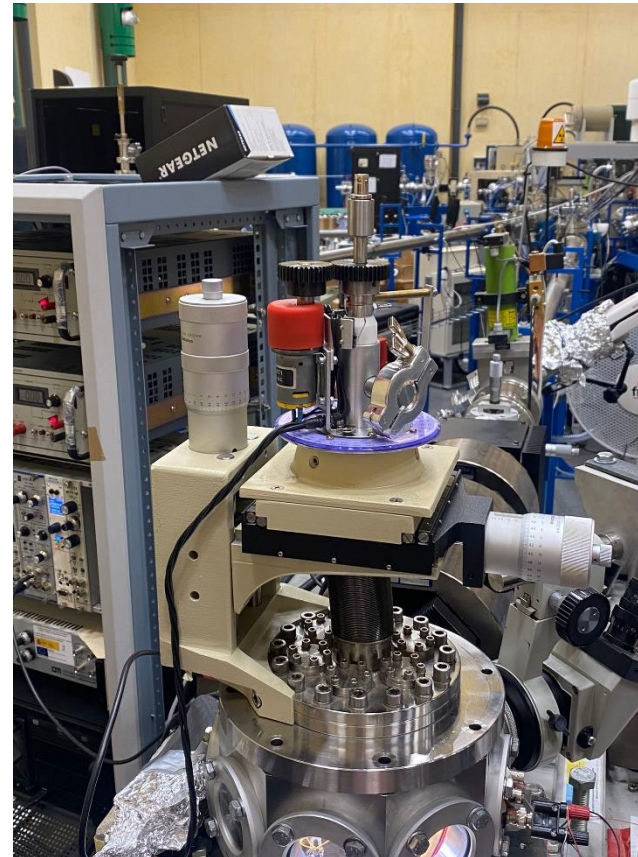




# Characterization with ions



Triple alpha source measurements in vacuum chamber (239Pu, 241Am, 244Cm)



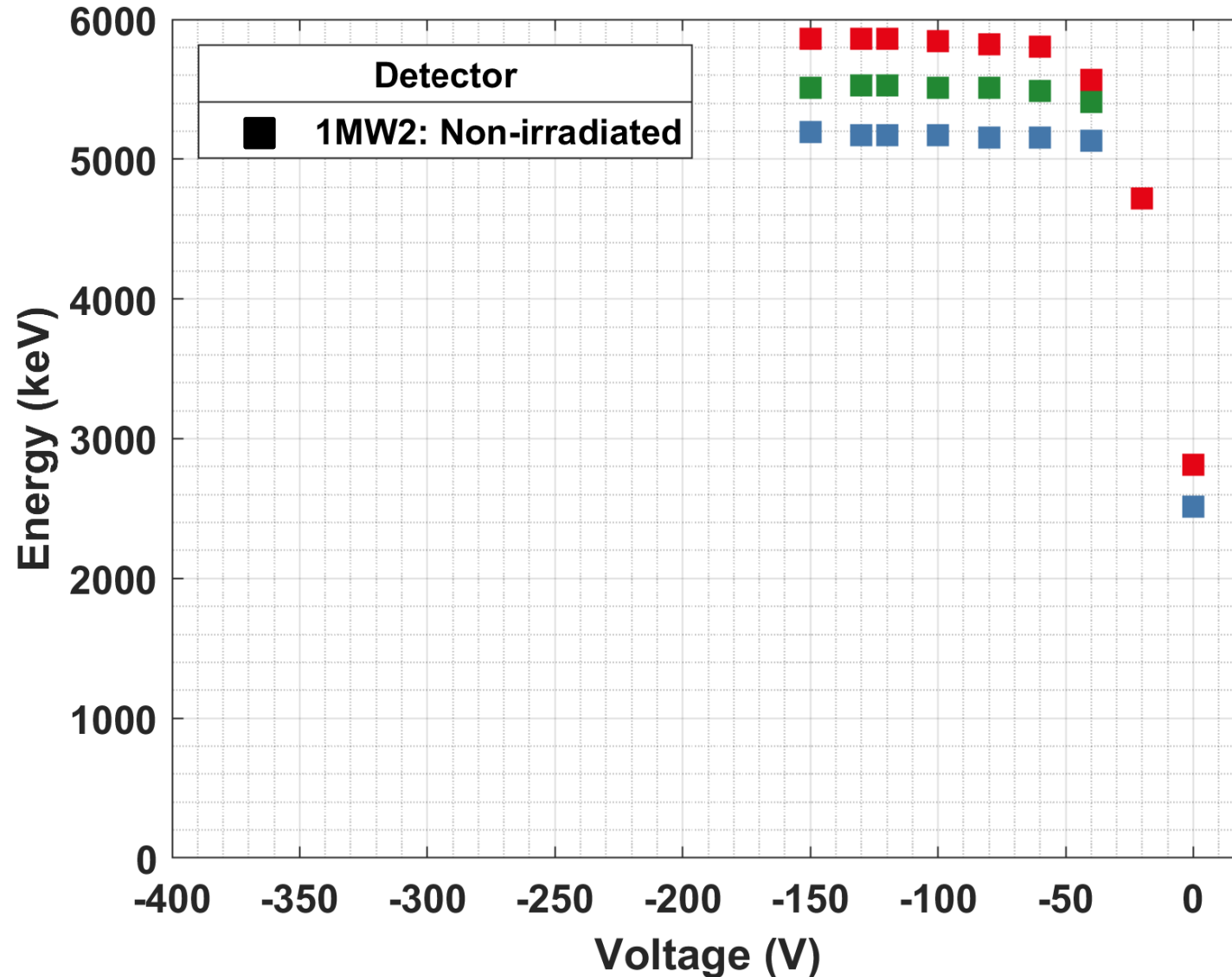
Proton measurements in microprobe beam line (2.7 MeV proton beam)

- **CCE absolute measurements**
- **Different polarization conditions**

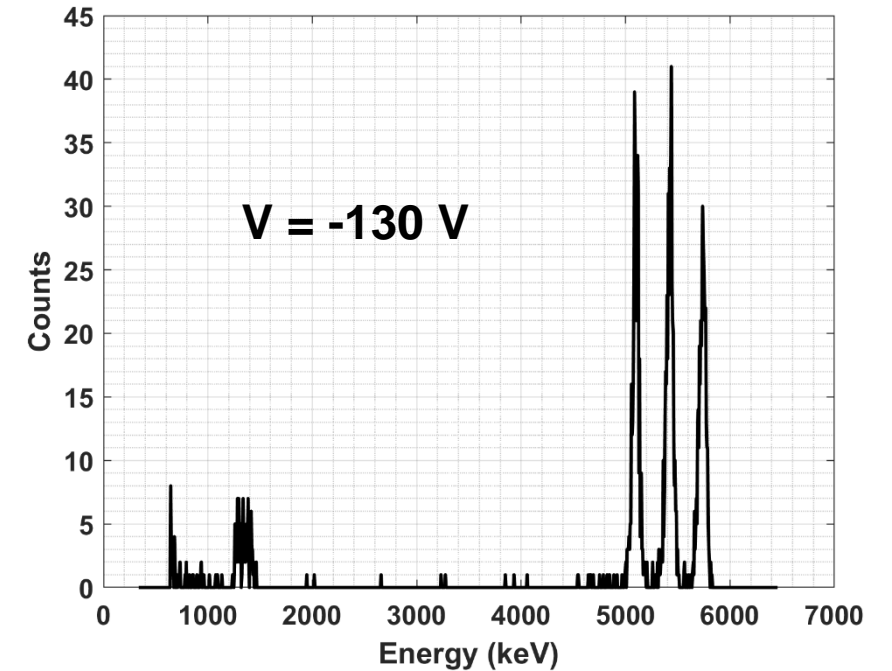
**SiC epitaxy : 50  $\mu$ m**

| Element | Energy (keV) | Range SiC ( $\mu$ m) |
|---------|--------------|----------------------|
| 244Cm   | 5746         | 19,8                 |
| 241Am   | 5424         | 18,3                 |
| 239Pu   | 5093         | 16,4                 |
| 1H      | 2700         | 52,0                 |

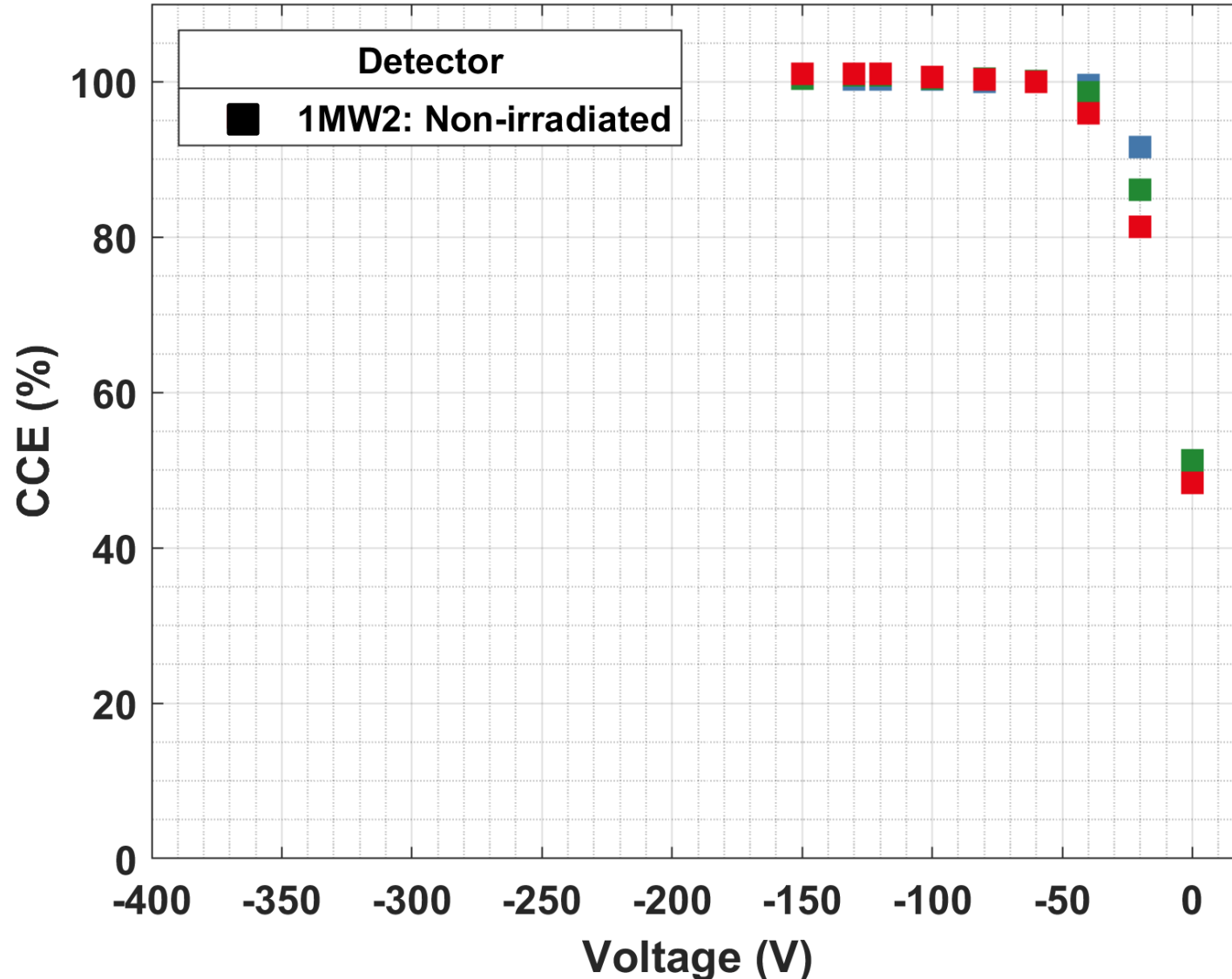
# Triple alpha source measurements



| Element           | Energy (keV) | Range SiC ( $\mu\text{m}$ ) |
|-------------------|--------------|-----------------------------|
| <sup>244</sup> Cm | 5746         | 19,8                        |
| <sup>241</sup> Am | 5424         | 18,3                        |
| <sup>239</sup> Pu | 5093         | 16,4                        |



# Triple alpha source measurements

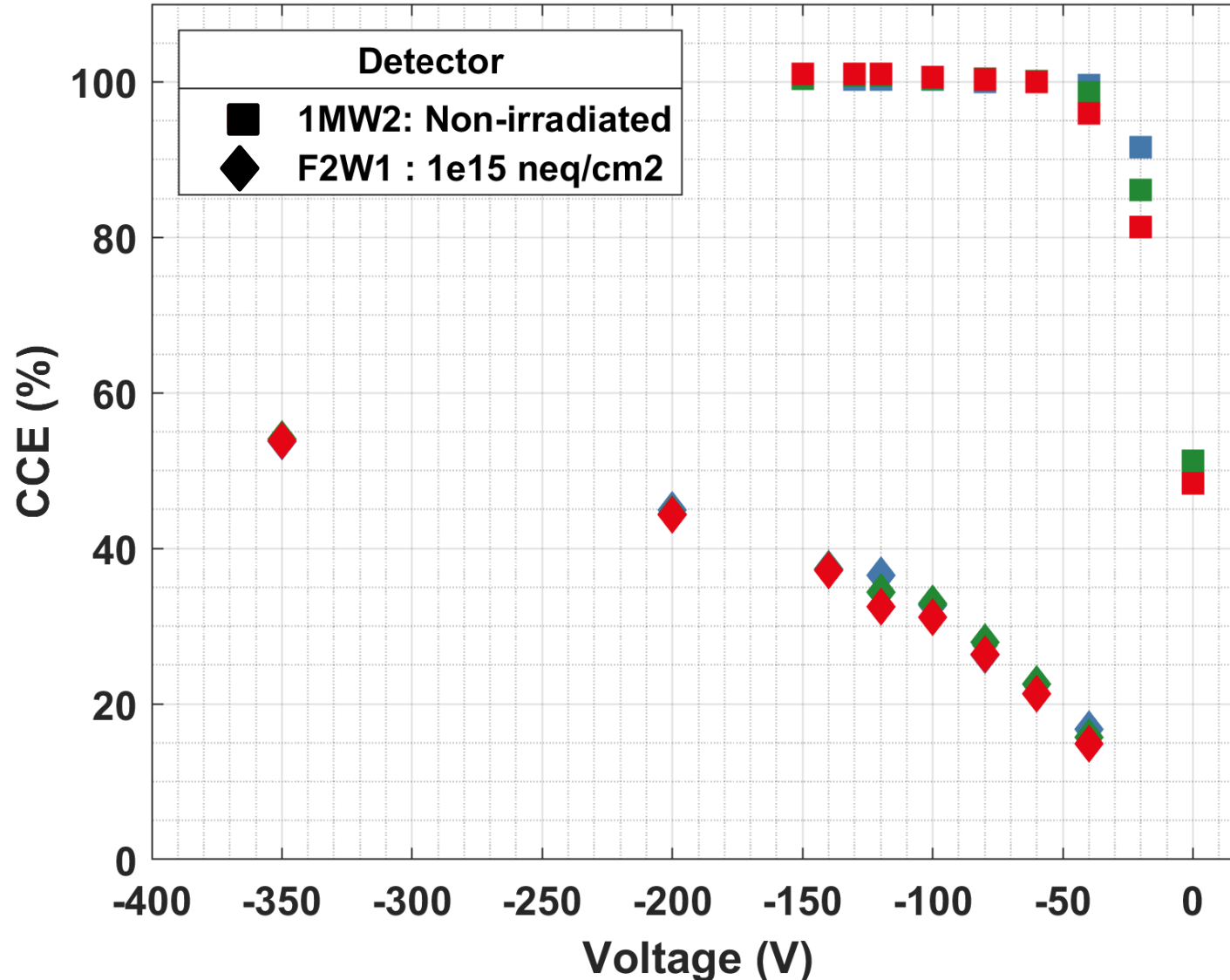


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- **TRIBIC measurement confirms 100 % CCE of pristine detector.**
- **Voltage limited by readout**
- **Plateau reached from 80 V.**

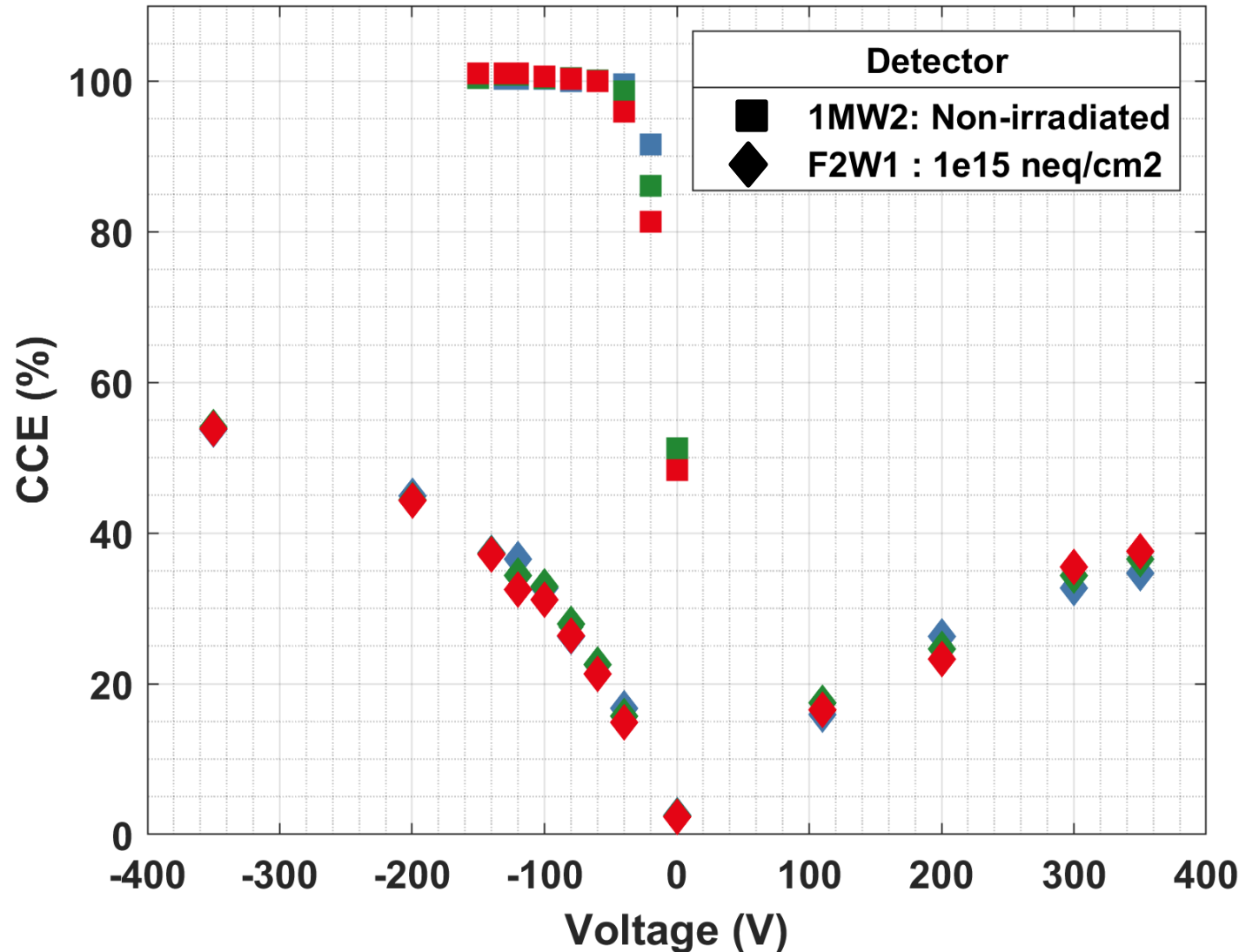


# Triple alpha source measurements



- Absolute CCE decrease of irradiated device
- No plateau reached in irradiated device
- Signal increase with bias

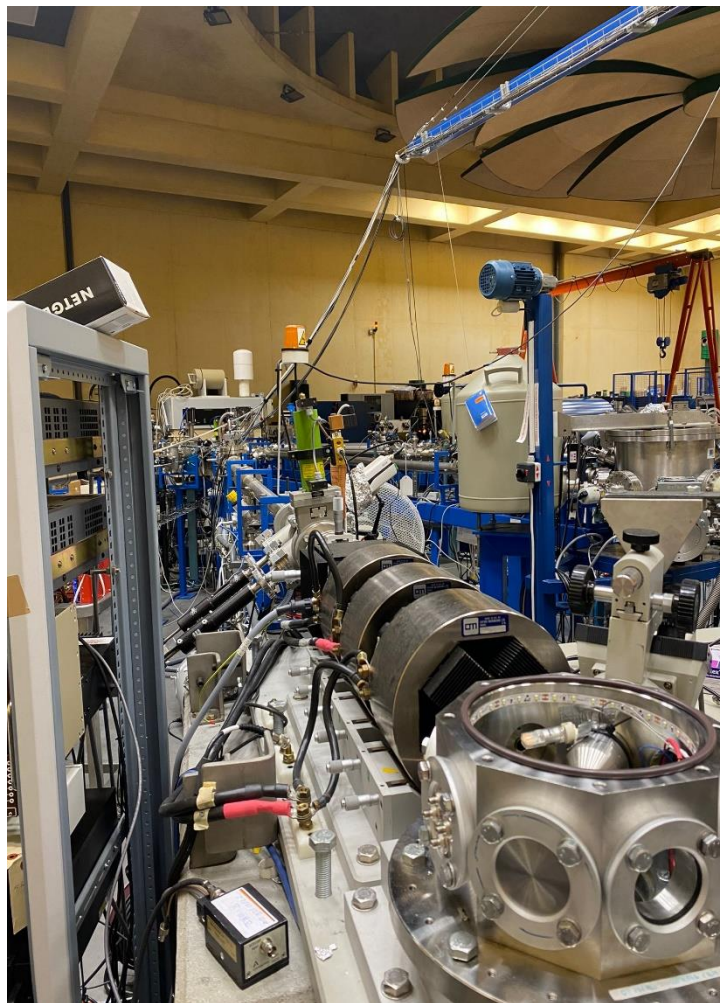
# Triple alpha source measurements



**-Forward polarization  
in irradiated device**

**- Smaller signal in  
forward than in  
reverse polarization**

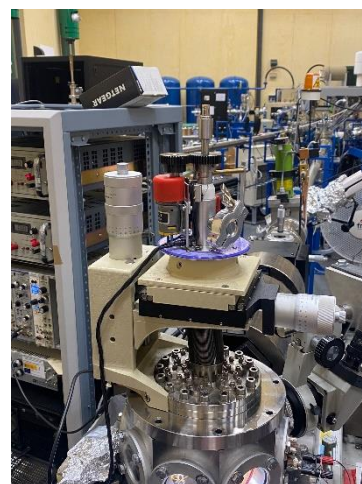
# Microprobe beam line at CNA



Nuclear Microprobe line



Tandem room



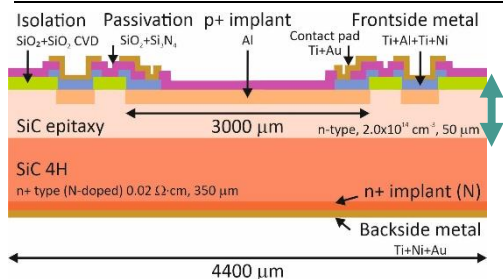
Rotating sample holder

## Why use the microprobe beam line?

- Small samples ( $3 \times 3 \text{ mm}^2$ )
- Good lateral resolution desired
- Low rate (to **avoid damage**)  $\sim 100 \text{ Hz}$
- **Rotating sample holder** with accuracy of  $1^\circ$ 
  - Angle-resolved IBIC



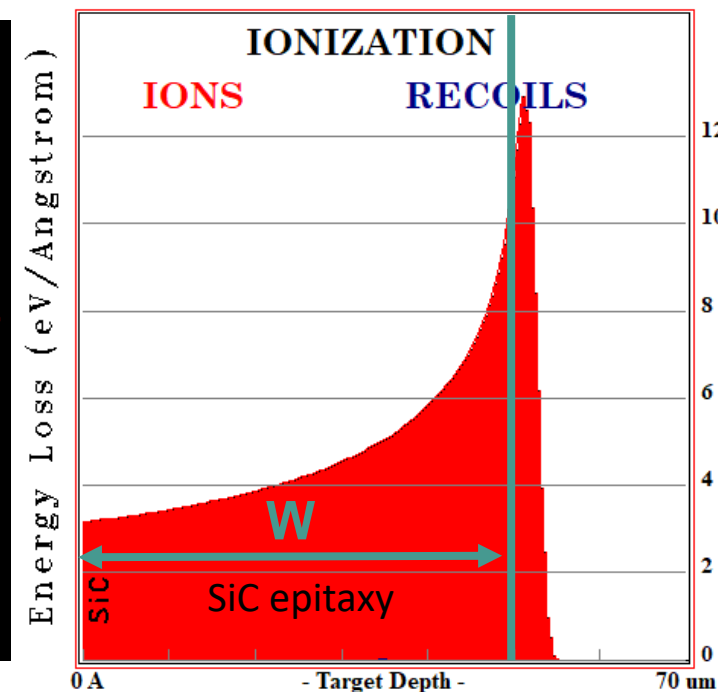
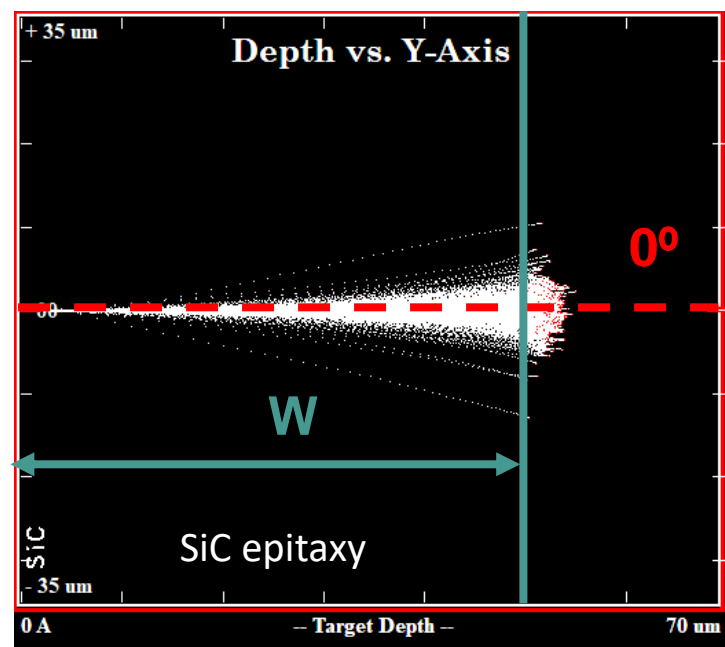
# Angle-Resolved IBIC



SiC epitaxy  $\rightarrow 50 \mu m$

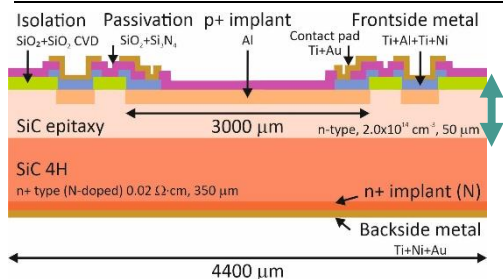
Range of  $2.7 \text{ MeV } H^+$  in SiC ( $3,22 \text{ g/cm}^3$ )  $\rightarrow 52 \mu m$  [SRIM simulation]

| Angle ( $^\circ$ ) | Projected range ( $\mu m$ ) |
|--------------------|-----------------------------|
| 0                  | 52                          |
| 20                 | 50                          |
| 40                 | 39                          |
| 60                 | 26                          |
| 80                 | 9                           |





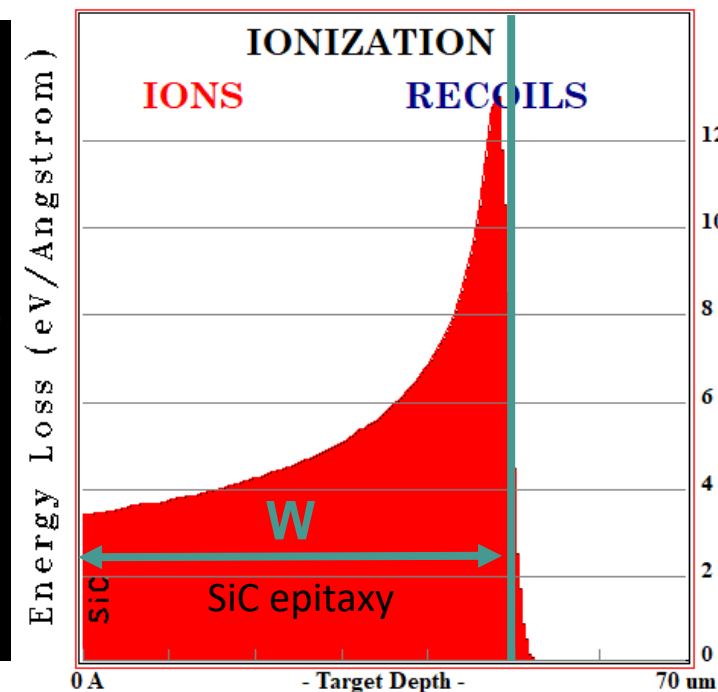
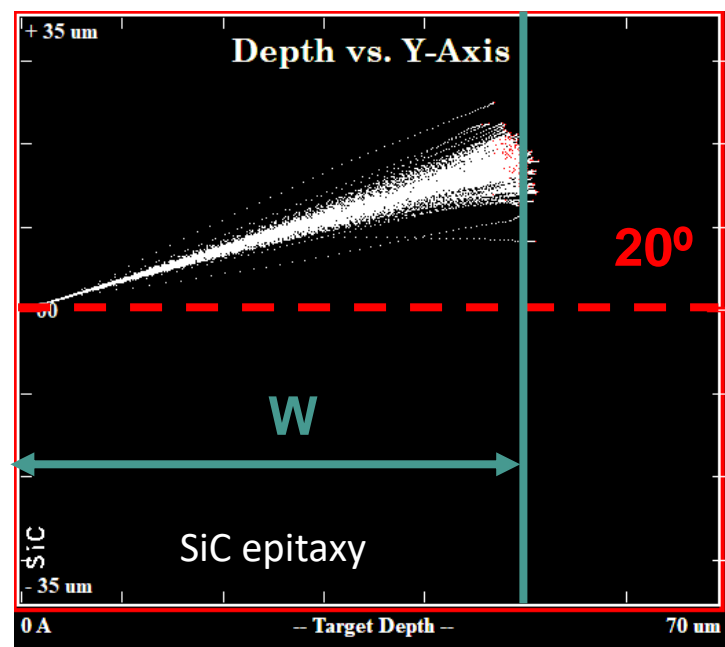
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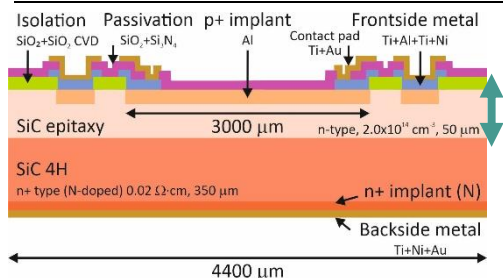
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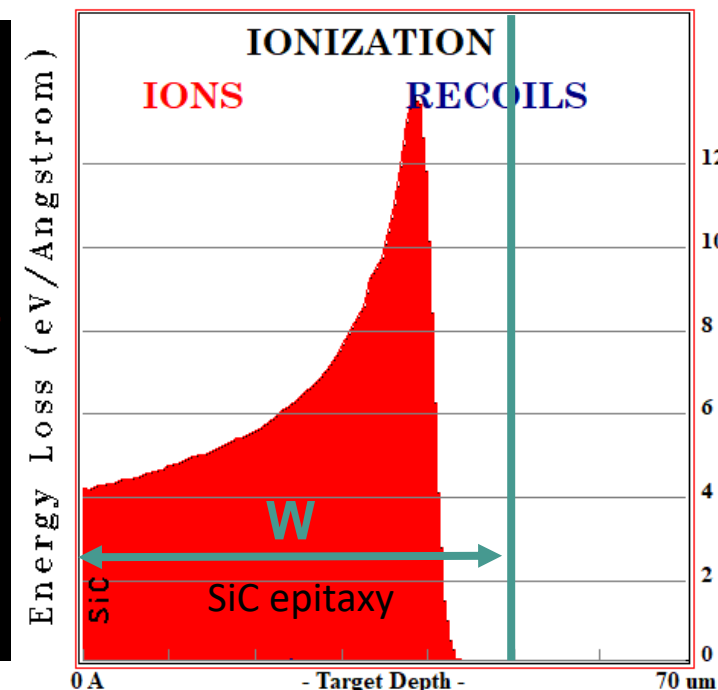
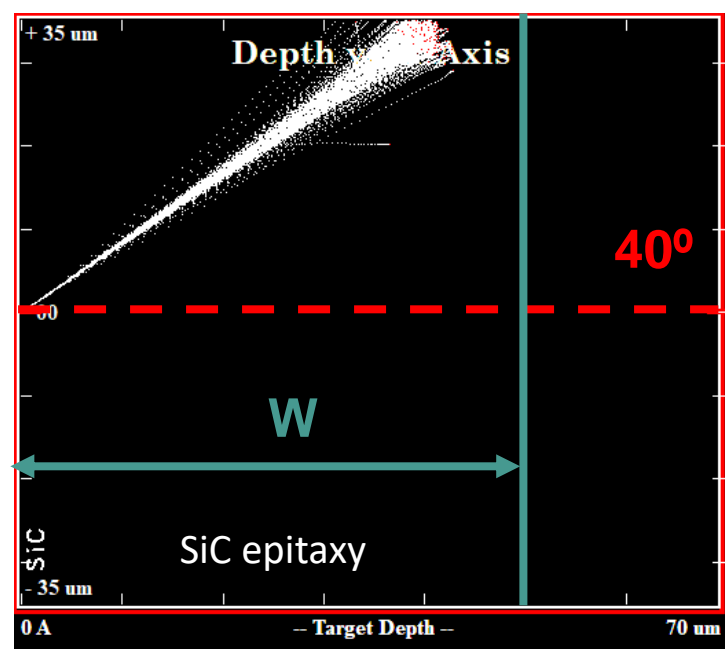
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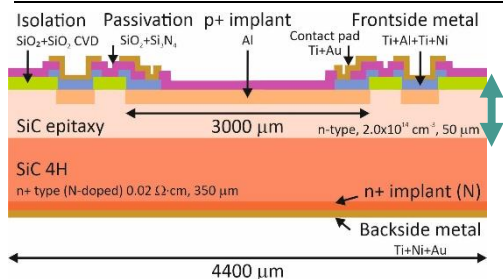
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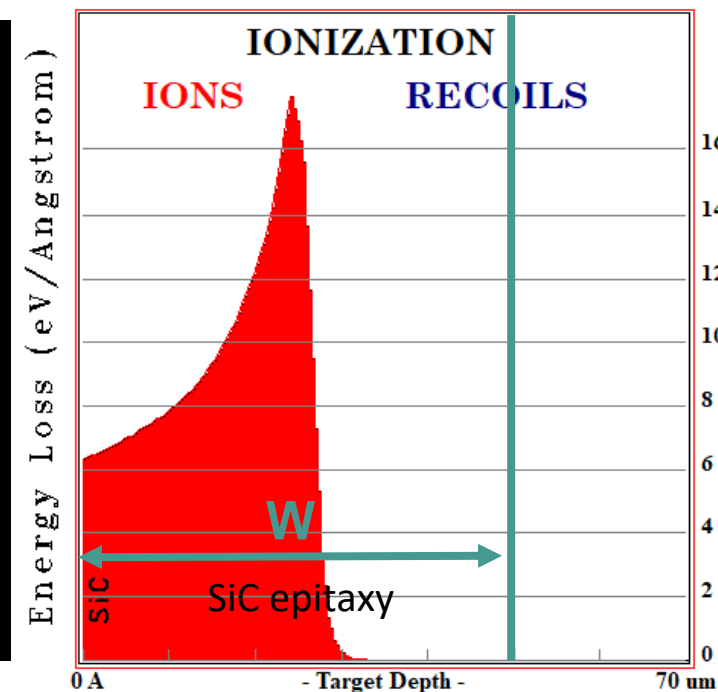
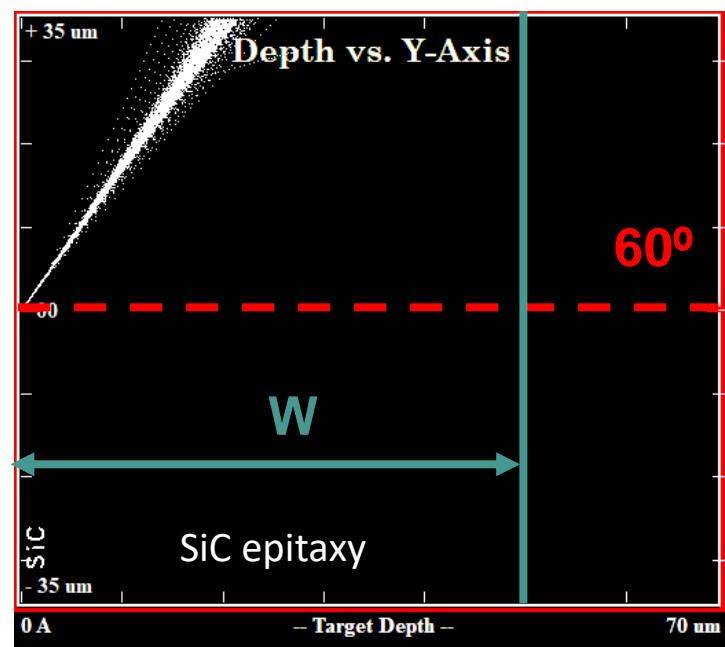
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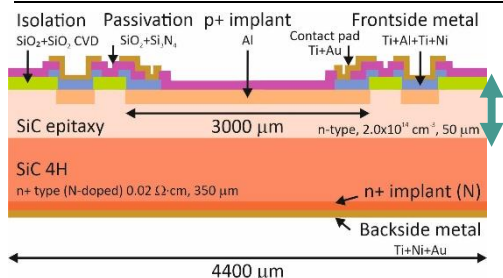
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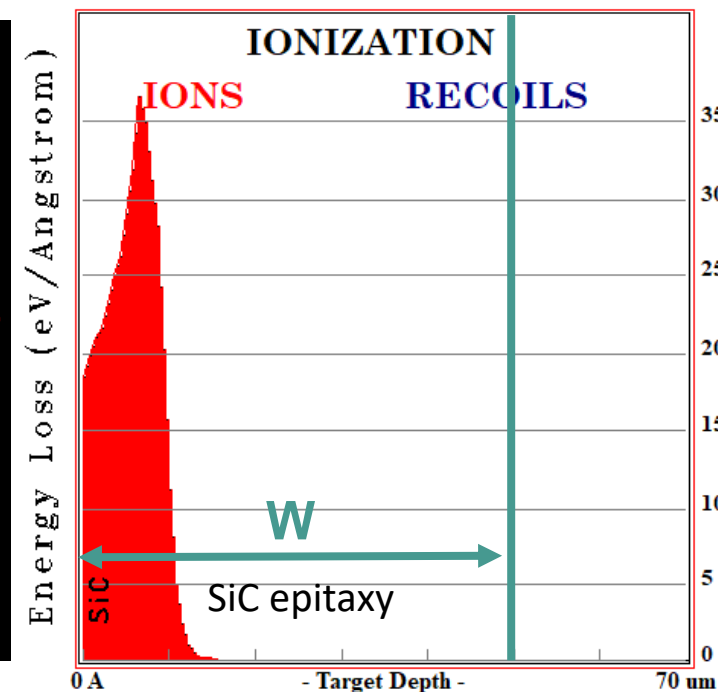
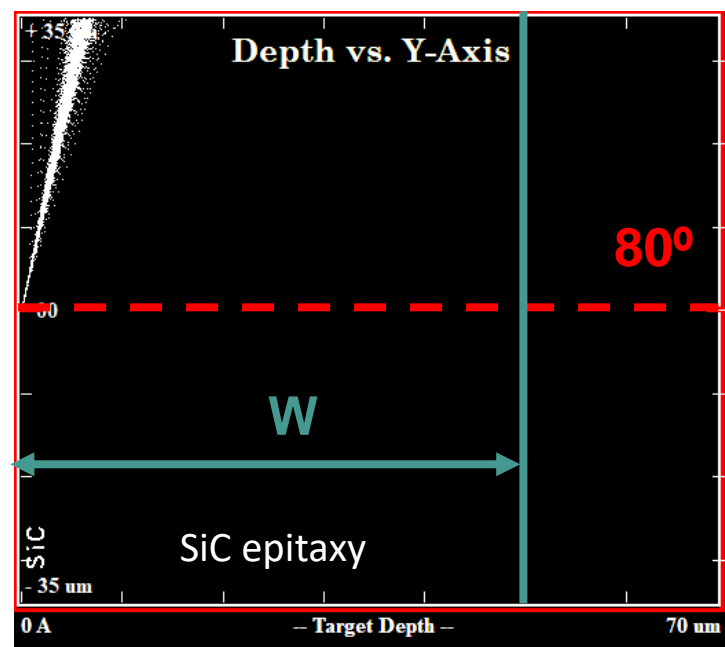
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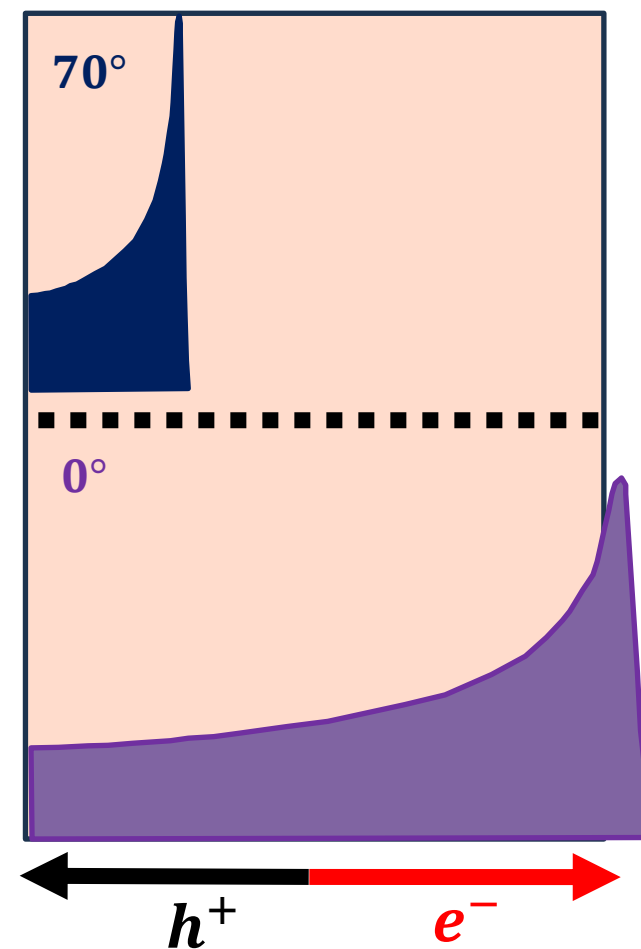
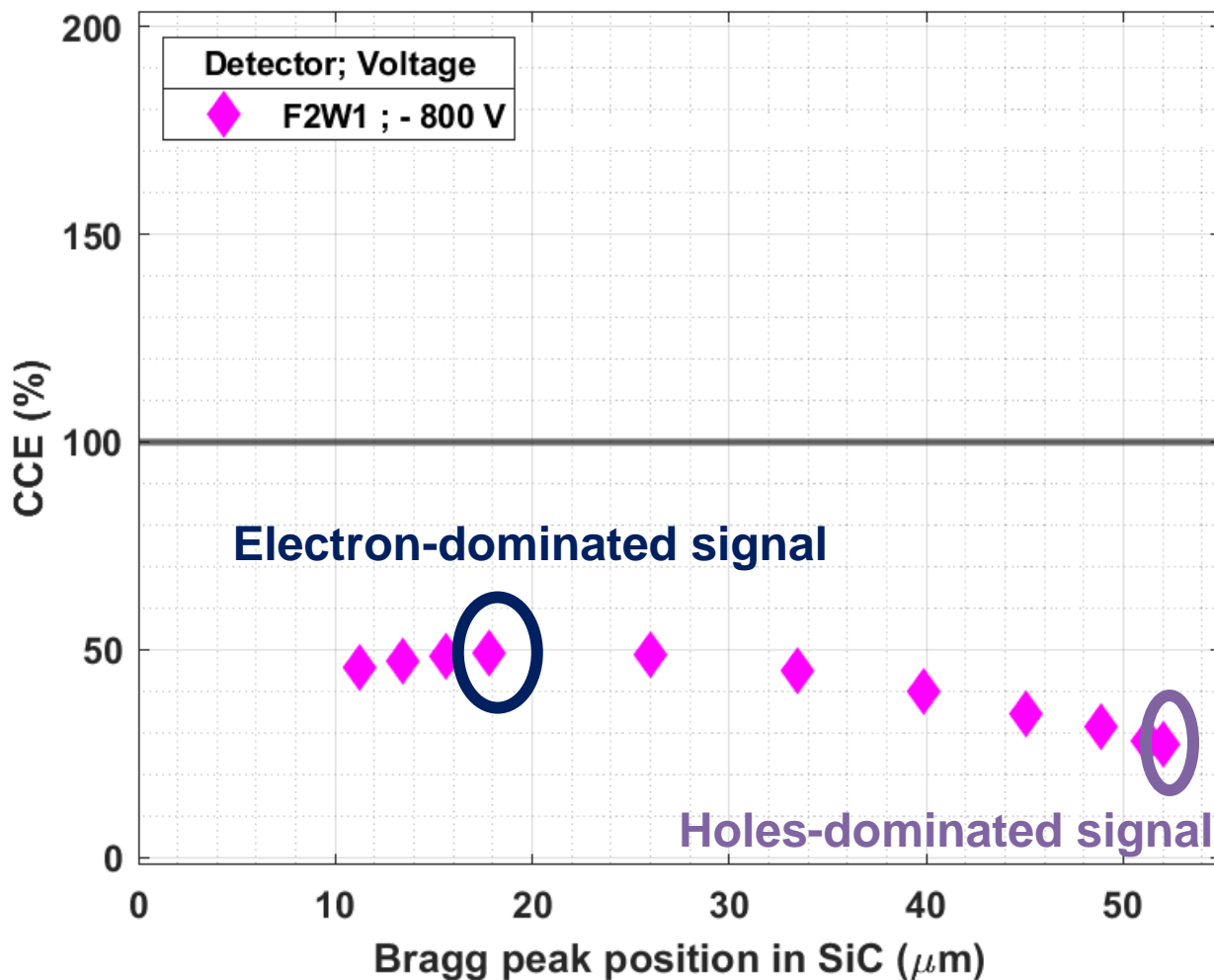
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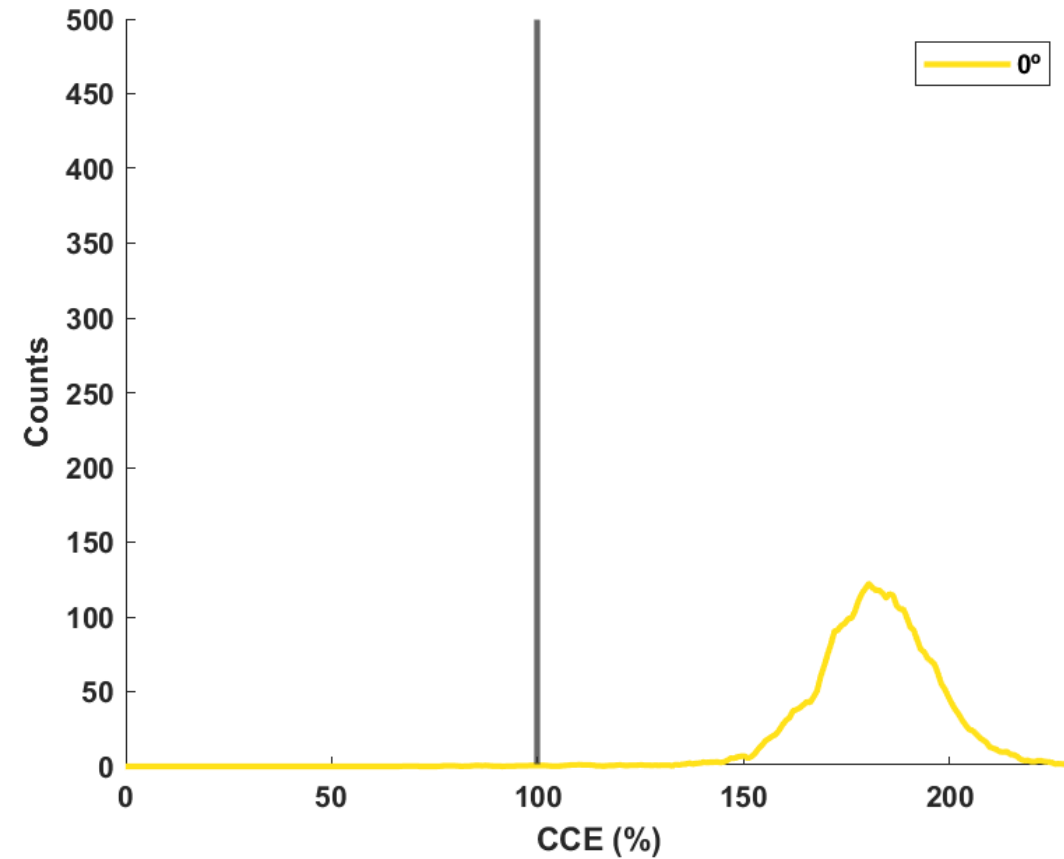
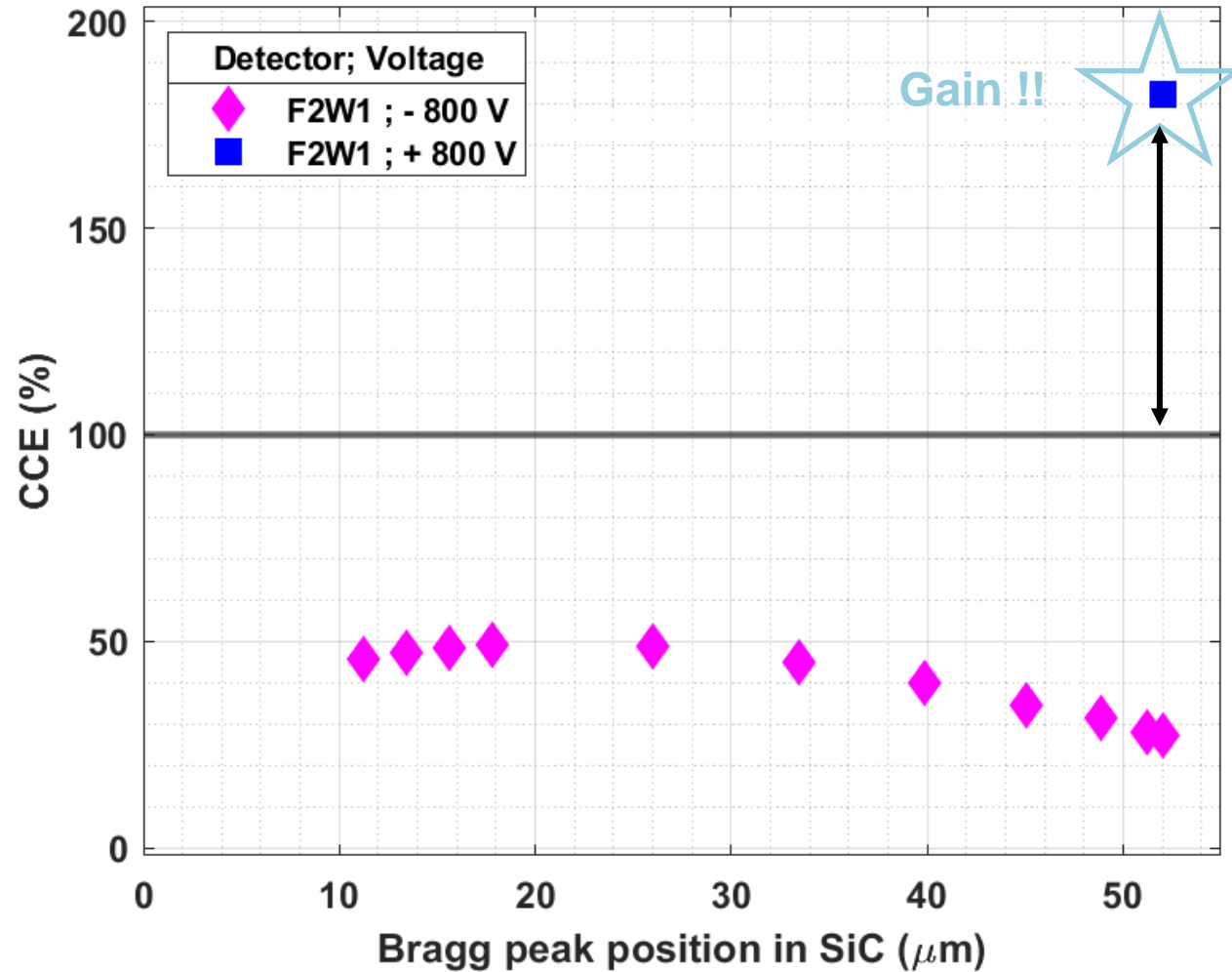
# 2.7 MeV H<sup>+</sup> : F2W1 reverse polarization



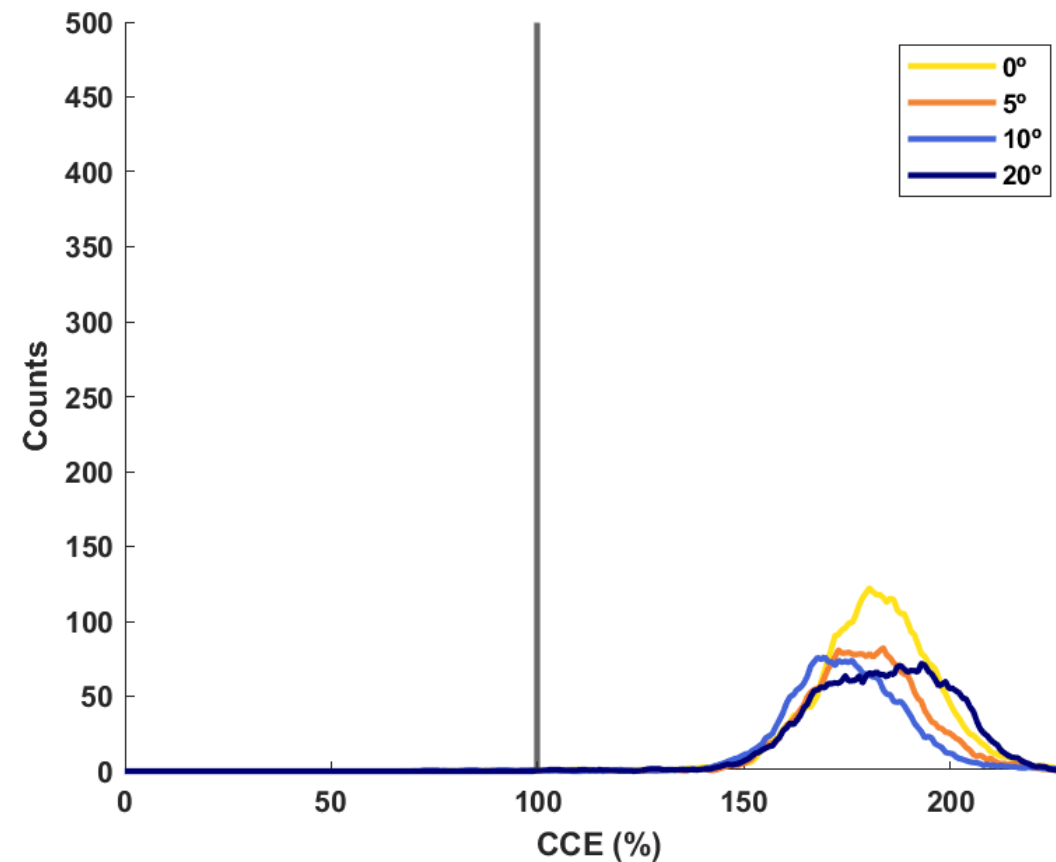
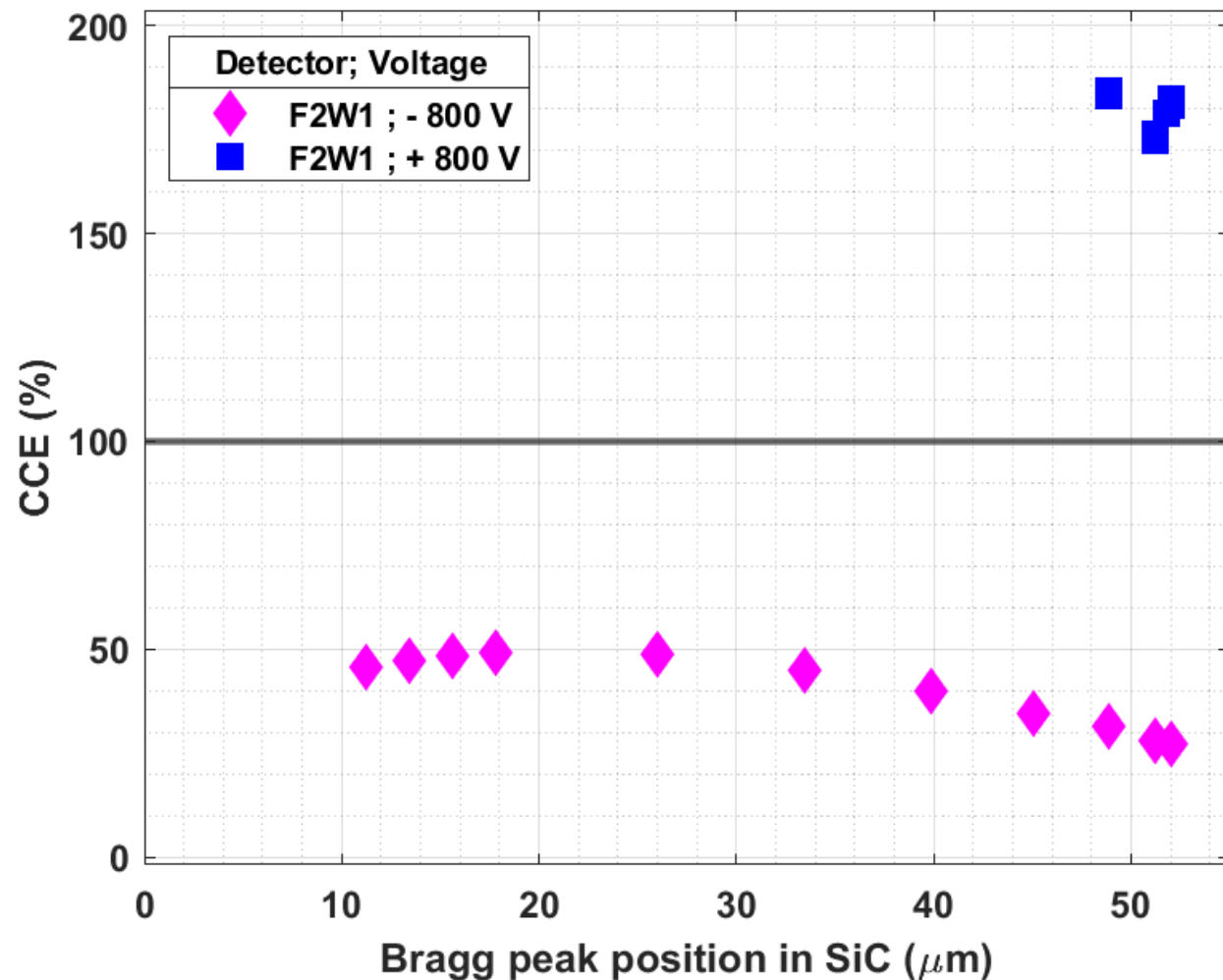
Higher signal when electron-dominated signal

Reverse polarization +

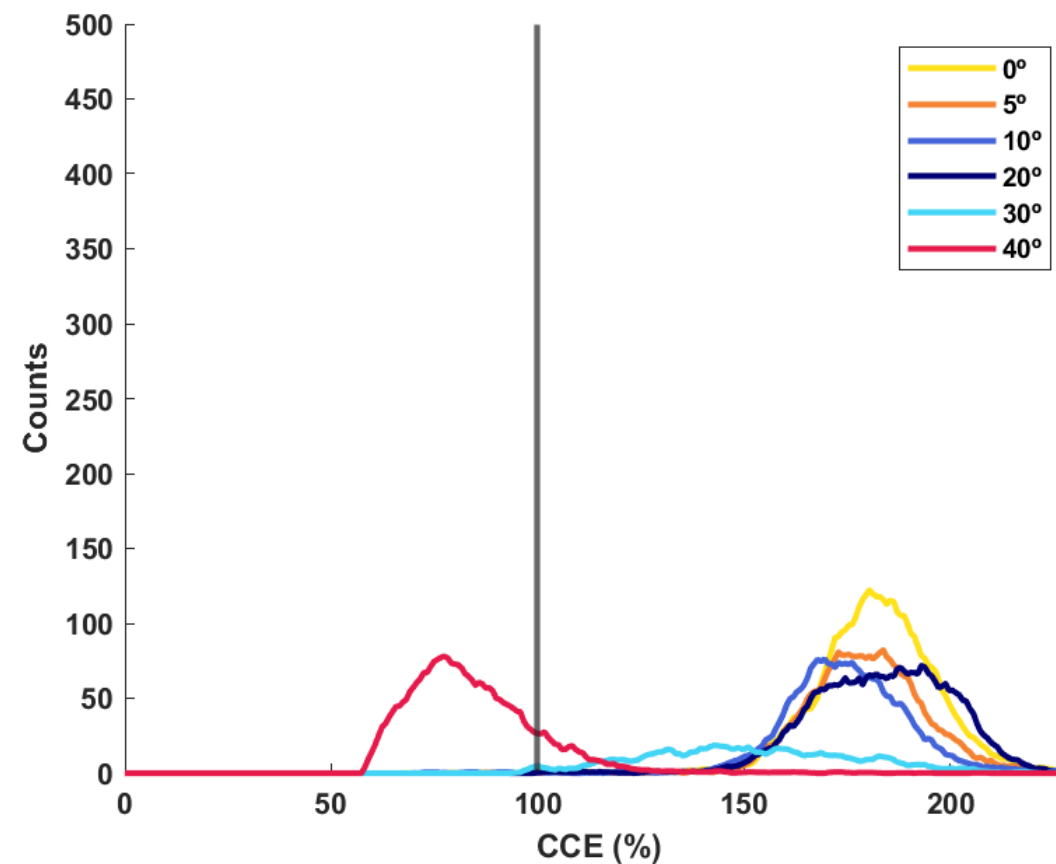
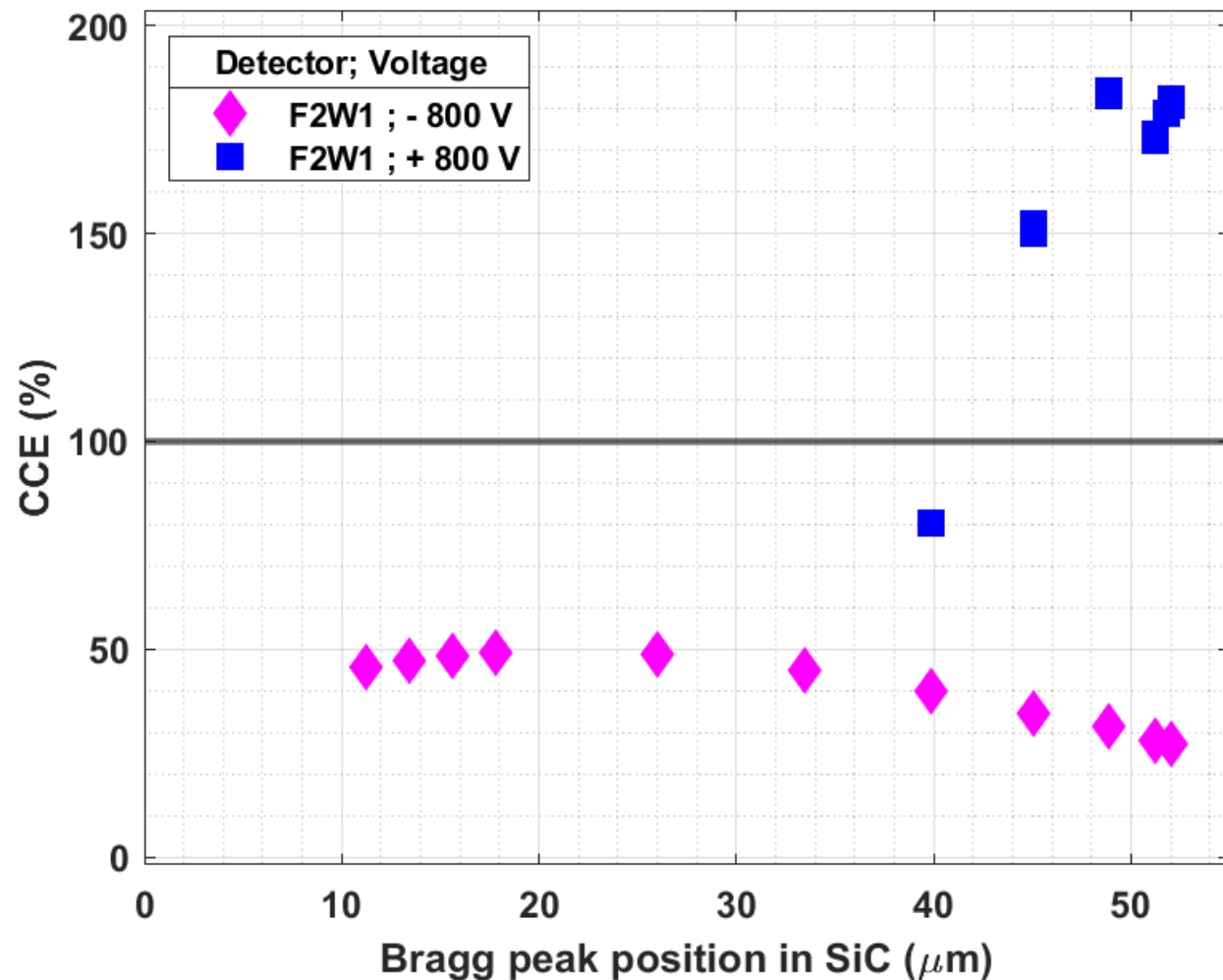
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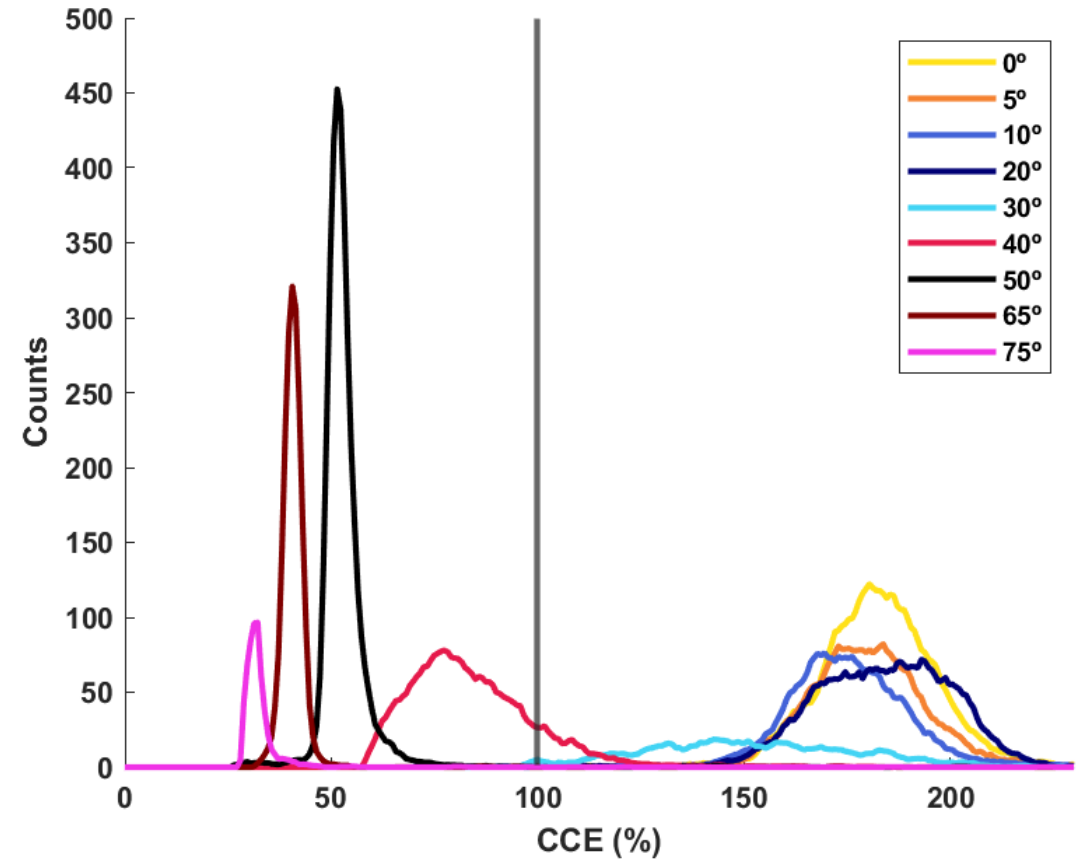
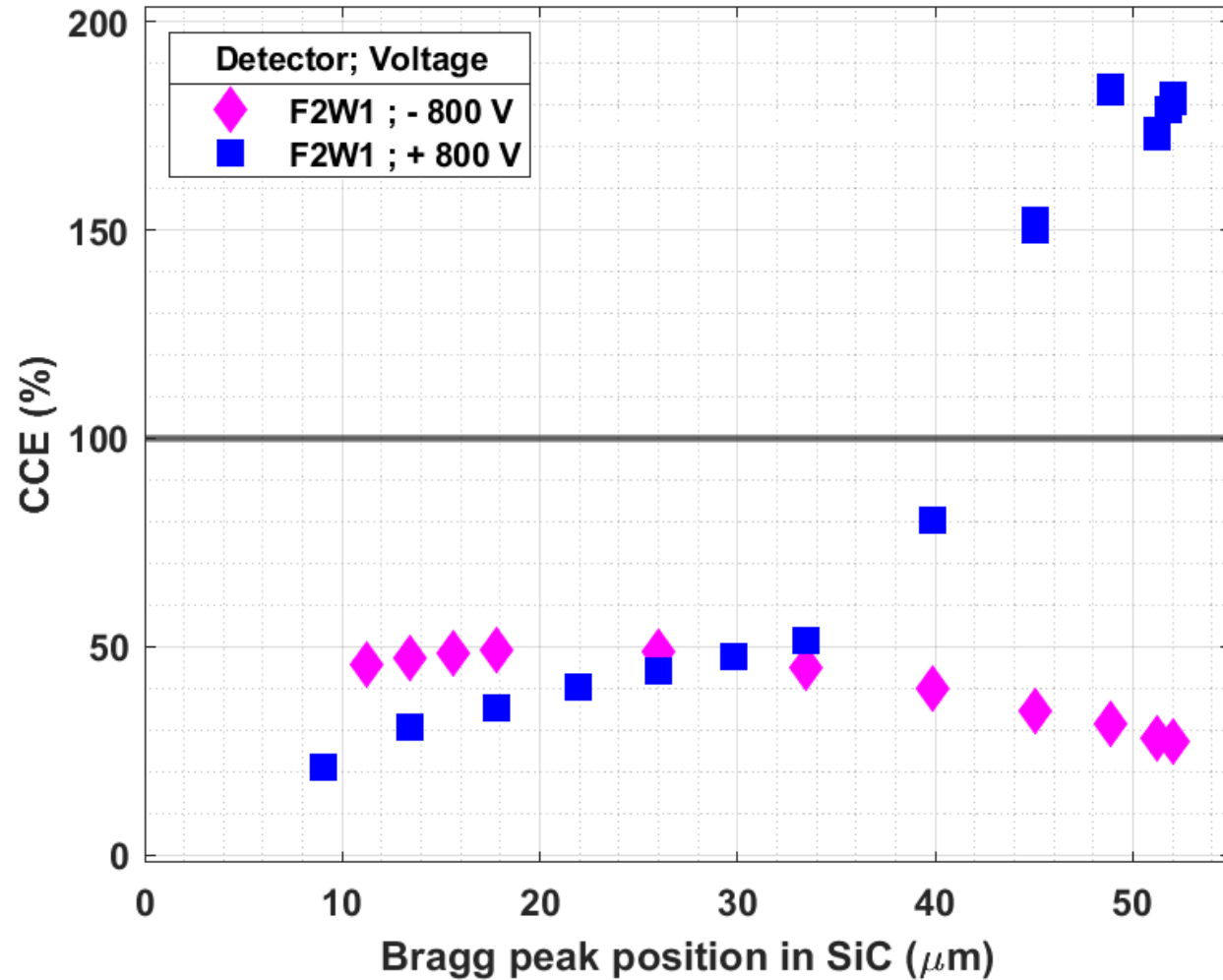


# 2.7 MeV H<sup>+</sup> : F2W1 forward polarization

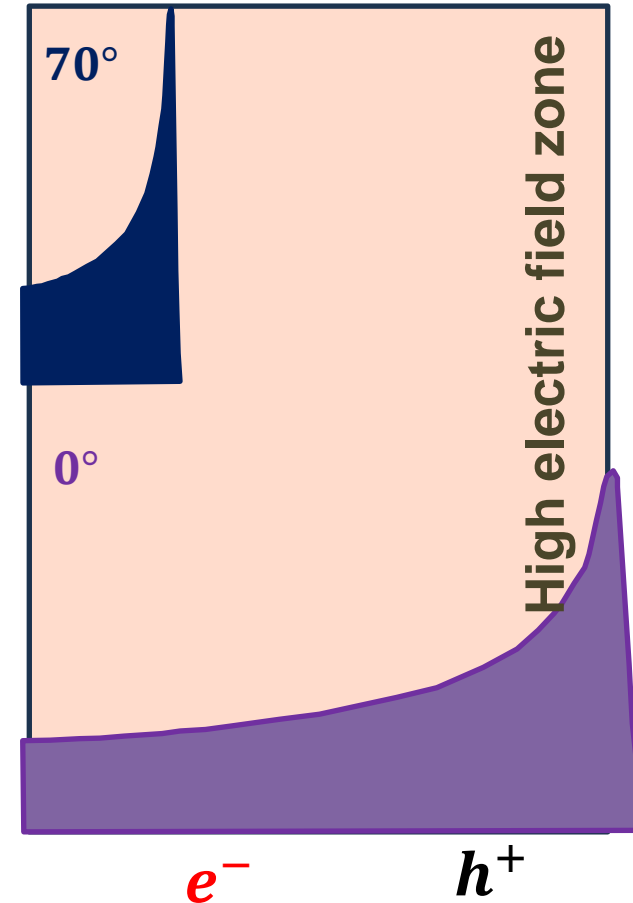
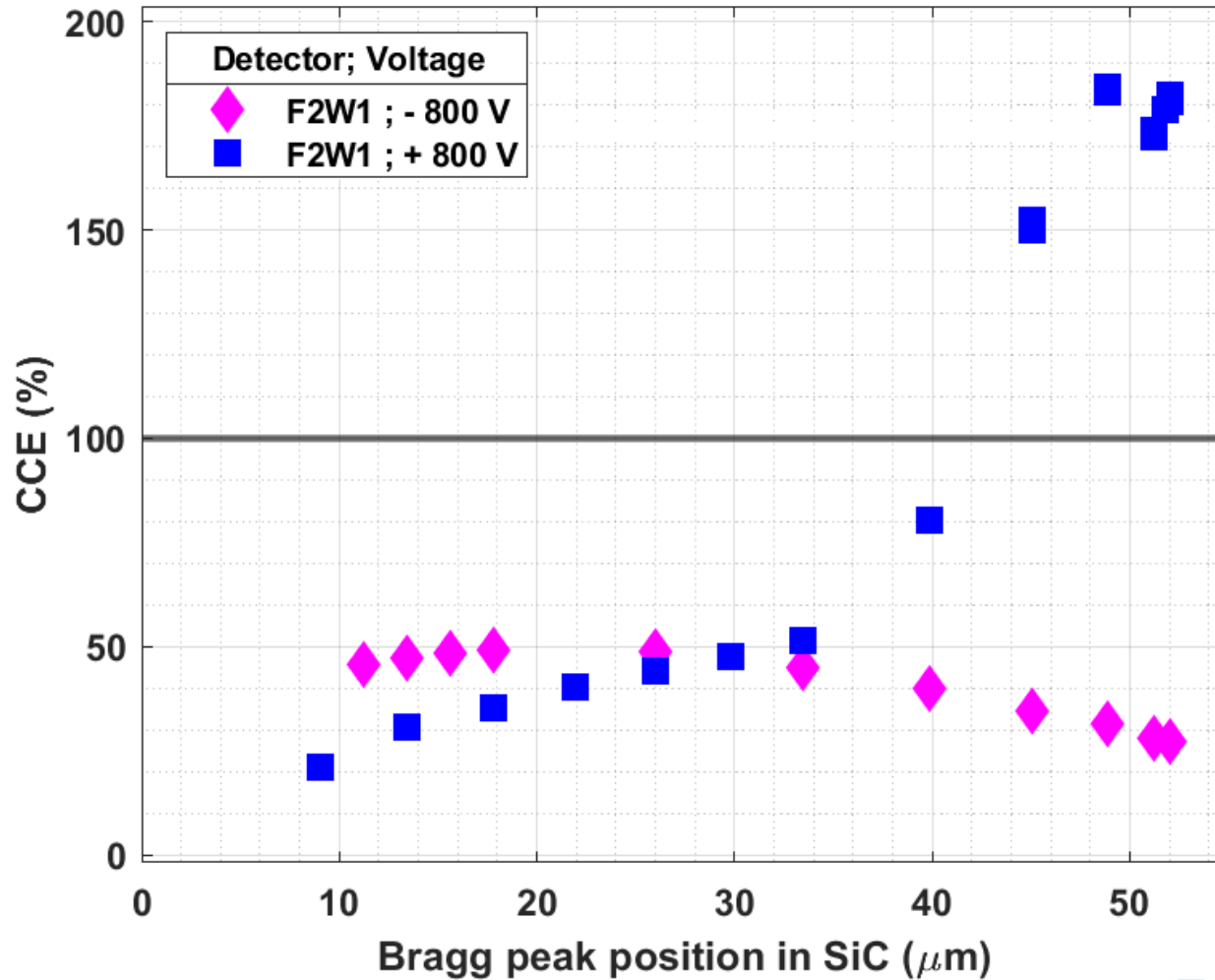




# 2.7 MeV H<sup>+</sup> : F2W1 forward polarization



# 2.7 MeV H<sup>+</sup> : F2W1 forward polarization



-High electric field zone

-Higher impact coefficient for holes in SiC

- Higher trapping probability for holes

+ Forward polarization

# Summary

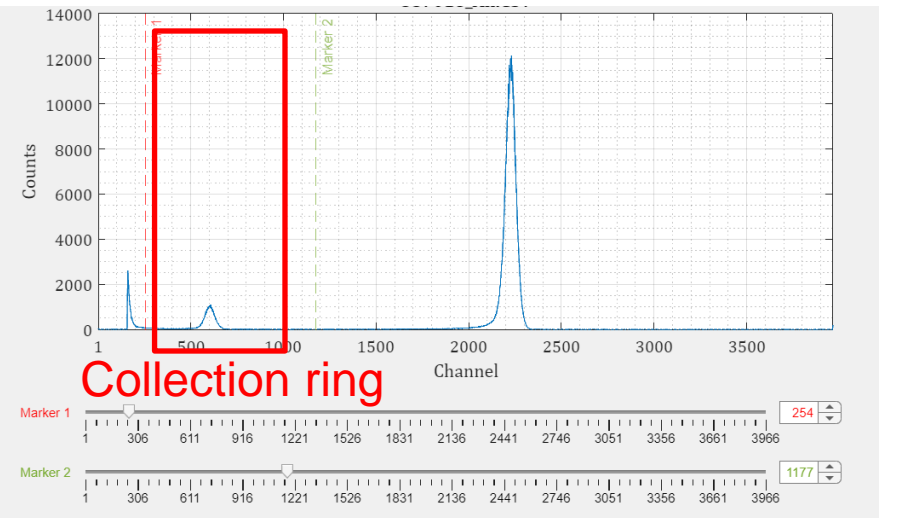
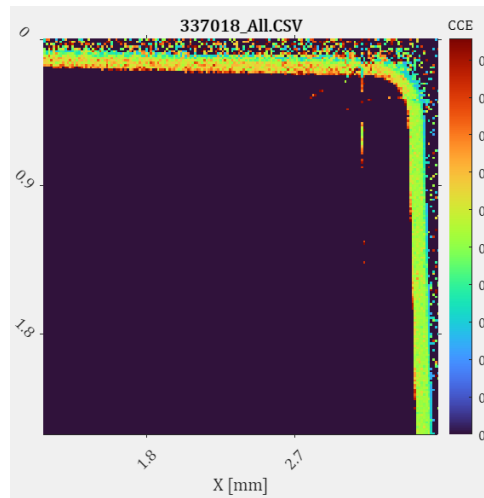
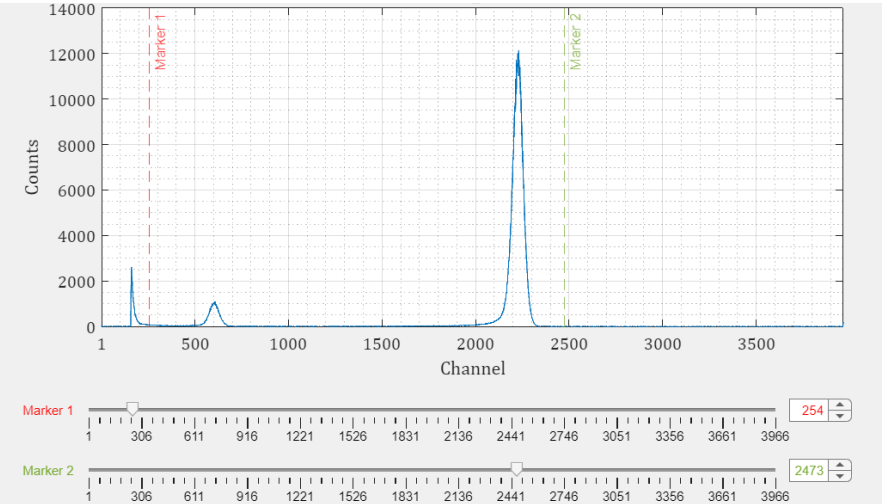
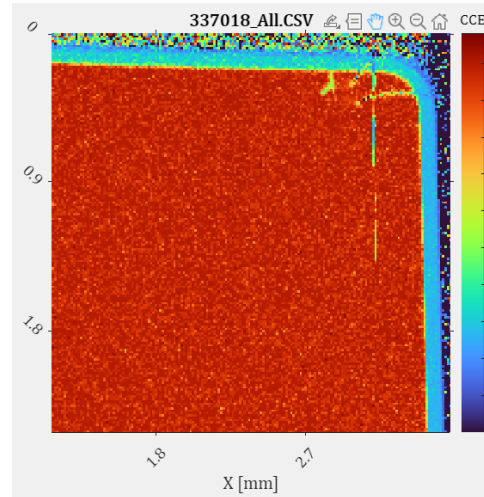
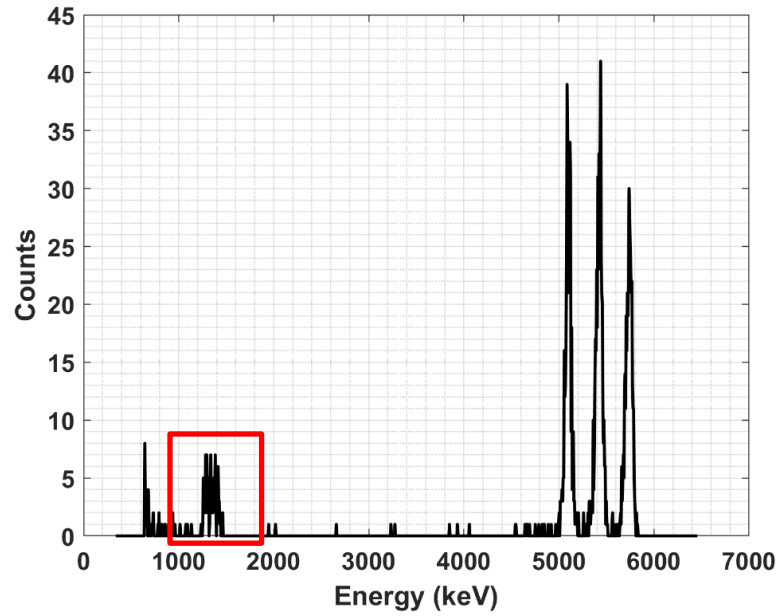
- Absolute measurement of the CCE as a function of voltage using ions in different polarizations.
- Irradiated devices higher trapping probability for holes.
- High electric field zone in forward polarization mode (holes multiplication).

# Thank you !

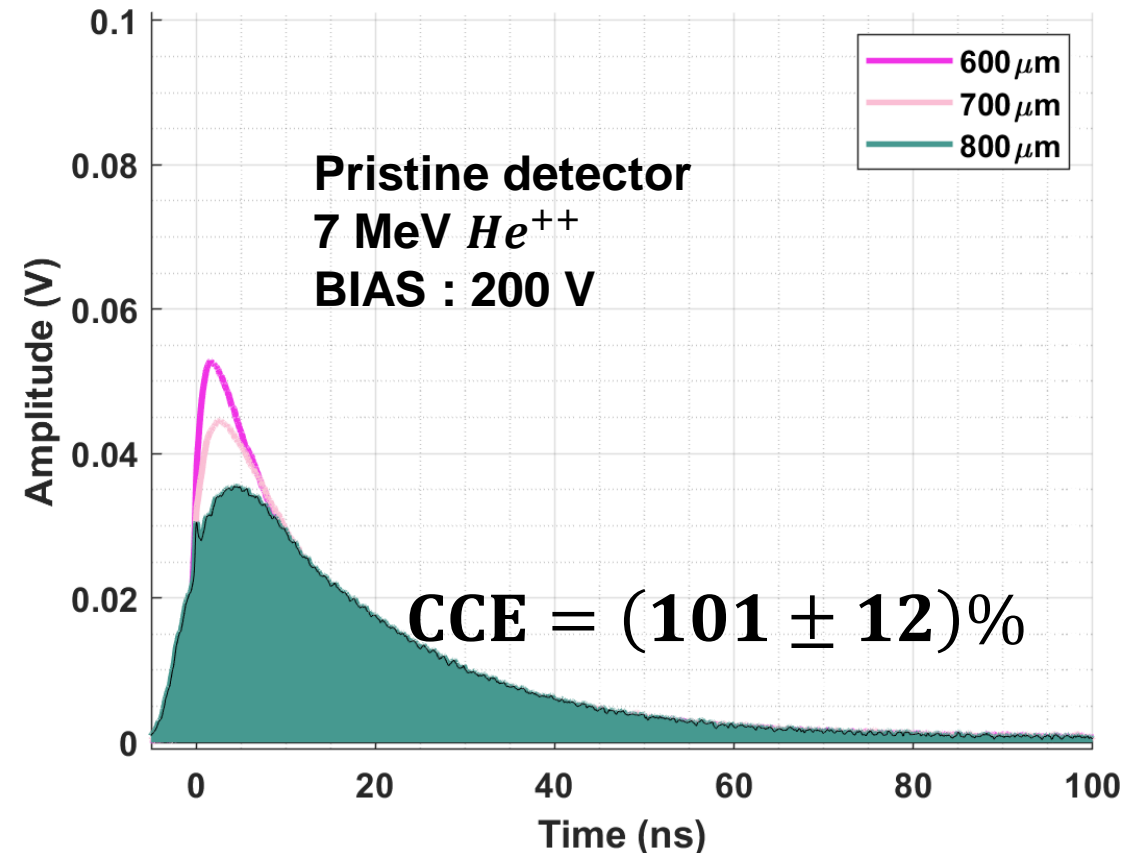
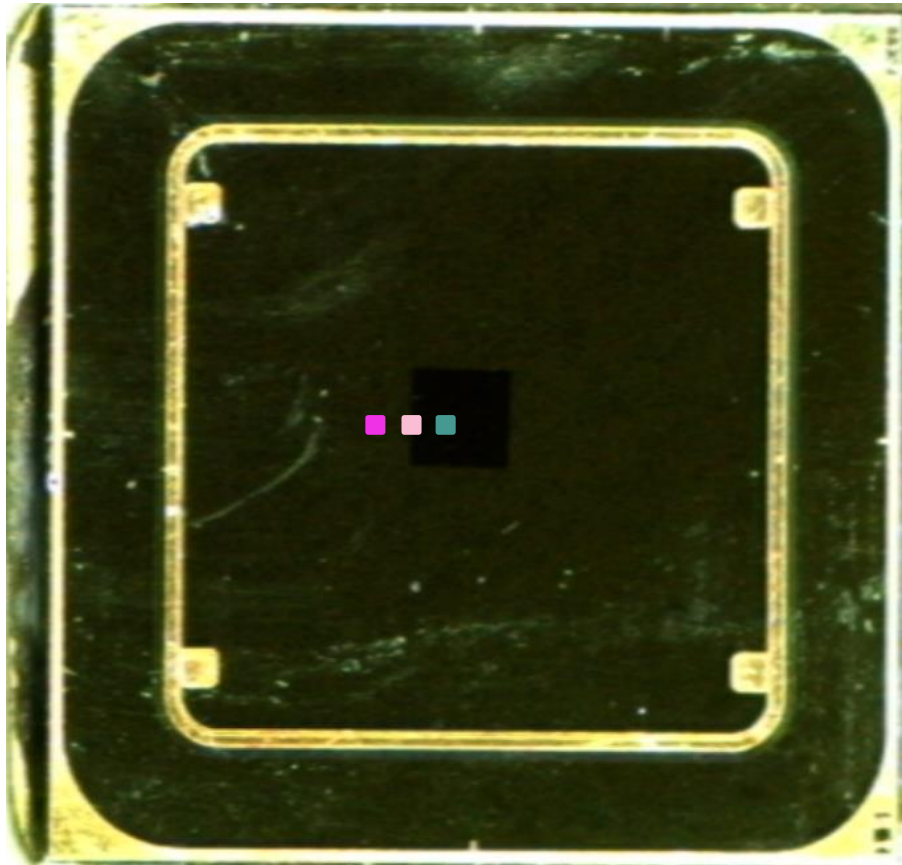
- M. Carmen Jiménez-Ramos acknowledges the support of this work through a VI PPIT-US contract.
- Carmen Torres-Muñoz acknowledges the support of this work through a contract that has been funded by the Unión Europea-NextGenerationEU y la Consejería de Universidad, Investigación e Innovación, de la Junta de Andalucía, mediante el Plan de Recuperación de Transformación y Resiliencia (PRTR) y el Plan Complementario de "Astrofísica", subproyecto C17.I01.P01.S17, Proyecto ASTRO21/1.4/4
- This research was funded by the Spanish Ministry of Science, Innovation and Universities grant numbers PID2023-148418NB-C44.



# Back-up slices



# Calculation of the absolute CCE value for the pristine detector



**Charge Collection Efficiency (CCE)**

$$CCE = \frac{\text{Charge induced}}{\text{Charge generated}}$$

# Calculation of the absolute CCE value for the pristine detector

## Theoretical calculation :

- Deposited energy in detector [SRIM simulation] :  $E = (6861 \pm 22) \text{ keV}$
- Electron-hole pair creation energy (4H-SiC) :  $\epsilon_{e^{-}-h^{+}} = 7.28 \text{ eV}$
- Elementary charge :  $e = 1.60 \times 10^{-19} \text{ C}$

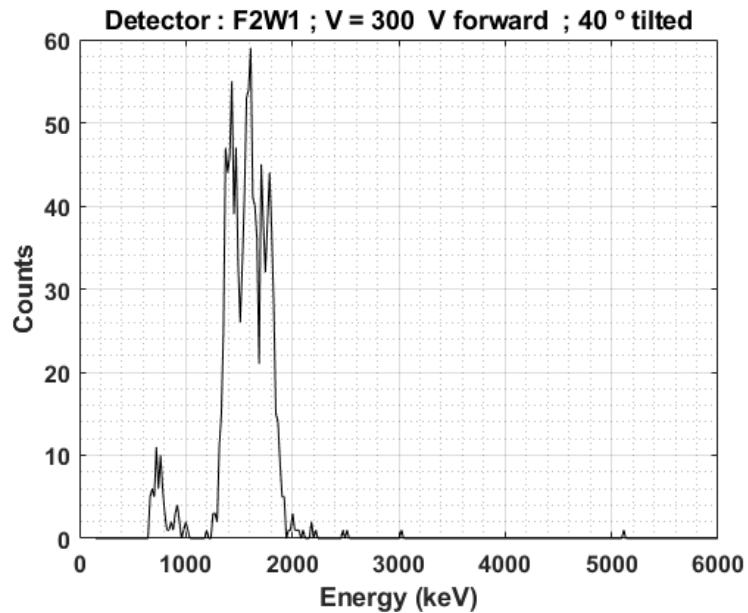
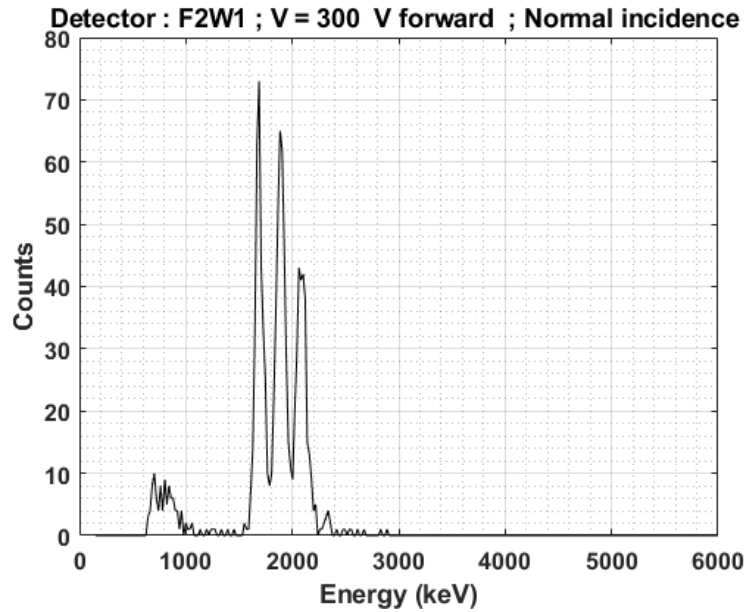
$$Q = \frac{E \cdot e}{\epsilon_{e^{-}-h^{+}}} = (1.510 \pm 0.005) \times 10^{-4} \text{ nC}$$

## Experimental results :

- Integral =  $(0.99 \pm 0.04) \text{ nWb}$
- Amplifier gain :  $(130 \pm 10)$
- Oscilloscope resistance :  $R = 50 \Omega$

$$Q = \frac{I}{R \cdot G} = (1.52 \pm 0.18) \times 10^{-4} \text{ nC}$$

**CCE = (101 ± 12)%**



| $E_{emission}$<br>(keV) | $E_{exp} [0^\circ]$<br>(keV) | $\frac{E_{emission} - E_{exp} [0^\circ]}{E_{emission}}$ (%) | $E_{exp} [40^\circ]$<br>(keV) | $\frac{E_{emission} - E_{exp} [40^\circ]}{E_{emission}}$ (%) | $E_{exp} [0^\circ] - E_{exp} [40^\circ]$ (keV) |
|-------------------------|------------------------------|---|-------------------------------|--|--|
| 5156                    | 1688                         | 67  | 1432                          | 72   | 256  |
| 5486                    | 1885                         | 66  | 1610                          | 71   | 275  |
| 5806                    | 2101                         | 64  | 1787                          | 69   | 314  |

| Element | Range SiC ( $\mu m$ ) | Range SiC tilting 40 ° ( $\mu m$ ) |
|---------|-----------------------|------------------------------------|
| 244Cm   | 19,8                  | 15,2                               |
| 241Am   | 18,3                  | 14,1                               |
| 239Pu   | 16,4                  | 12,5                               |